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**Semiconductor devices – Micro-electromechanical devices –
Part 41: RF MEMS circulators and isolators**

**Dispositifs à semiconducteurs – Dispositifs microélectromécaniques –
Partie 41: Circulateurs et isolateurs à MEMS RF**





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CONTENTS

FOREWORD	5
1 Scope	7
2 Normative references	7
3 Terms and definitions	7
3.1 General terms	8
3.2 RF characteristics parameters	8
4 Essential ratings and characteristics	9
4.1 Identification and types	9
4.2 Application and specification description	9
4.3 Limiting values and operating conditions	10
4.4 RF characteristics	10
4.5 Reliability characteristics	10
4.6 Additional information	11
5 Measuring methods	11
5.1 General	11
5.1.1 General precautions	11
5.1.2 Characteristic impedance	11
5.1.3 Measurement procedure	11
5.1.4 Handling precautions	12
5.2 Insertion loss (L_{ins})	12
5.2.1 Purpose	12
5.2.2 Circuit diagram	12
5.2.3 Principle of measurement	15
5.2.4 Precautions to be observed	15
5.2.5 Measurement procedure	15
5.2.6 Specified conditions	16
5.3 Isolation (L_{iso})	17
5.3.1 Purpose	17
5.3.2 Circuit diagram	17
5.3.3 Principle of measurement	17
5.3.4 Precautions to be observed	18
5.3.5 Measurement procedure	18
5.3.6 Specified conditions	19
5.4 Return loss (L_{ret})	19
5.4.1 Purpose	19
5.4.2 Circuit diagram	19
5.4.3 Principle of measurement	19
5.4.4 Precautions to be observed	20
5.4.5 Measurement procedure	20
5.4.6 Specified conditions	21
5.5 Voltage standing wave ratio ($VSWR$) (optional)	21
5.5.1 Purpose	21
5.5.2 Circuit diagram	21
5.5.3 Principle of measurement	21
5.5.4 Precautions to be observed	22
5.5.5 Measurement procedure	22

5.5.6	Specified conditions.....	23
5.6	Input impedance (Z_{in}) (optional).....	23
5.6.1	Purpose.....	23
5.6.2	Circuit diagram	23
5.6.3	Principle of measurement	23
5.6.4	Precautions to be observed	24
5.6.5	Measurement procedure	24
5.6.6	Specified conditions.....	25
5.7	Magnetic leakage (optional)	25
5.7.1	Purpose.....	25
5.7.2	System diagram.....	25
5.7.3	Principle of measurement	26
5.7.4	Precautions to be observed	26
5.7.5	Measurement procedure	26
5.7.6	Specified conditions.....	26
6	Reliability (performance) test.....	26
6.1	General.....	26
6.2	Power handling capability	27
6.3	Life time.....	27
6.4	Operating temperature	27
6.5	Shock testing	27
6.6	Vibration testing.....	28
6.7	Bond/Solder shear testing.....	28
Annex A (informative)	General description of circulators and isolators	29
Bibliography.....	32	

Figure 1 – Terminals of RF MEMS circulators	9
Figure 2 – RF MEMS isolator with terminated load.....	9
Figure 3 – Measurement procedure of RF MEMS circulators/isolators.....	11
Figure 4 – Measuring circuit diagram of the circulator with 4-port network analysers.....	13
Figure 5 – Measuring circuit diagram of the isolator with 4-port network analysers.....	13
Figure 6 – Measuring circuit diagram of the circulator with 2-port network analysers.....	14
Figure 7 – Measuring circuit diagram of the isolator with 2-port network analysers.....	14
Figure 8 – Insertion loss of the RF MEMS circulator/isolator	15
Figure 9 – Isolation of the RF MEMS circulator/isolator	17
Figure 10 – Return loss of the RF MEMS circulator/isolator	20
Figure 11 – Smith Chart plot of input impedance of RF MEMS circulators/isolators	24
Figure 12 – Near-field scanning measurement system	26
Figure 13 – Block diagram of a test setup for evaluating the reliability of the RF MEMS circulator.....	27
Figure A.1 – Signal transmission in circulators.....	29
Figure A.2 – Signal transmission in isolators.....	30
Figure A.3 – Typical structure of RF MEMS circulators/isolators	30
Figure A.4 – Typical RF MEMS circulators/ isolators	31

Table 1 – Limiting values and operating conditions	10
Table 2 – RF characteristics	10
Table 3 – Reliability characteristics	10

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Full information on the voting for its approval can be found in the report on voting indicated in the above table.

The language used for the development of this International Standard is English.

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SEMICONDUCTOR DEVICES – MICRO-ELECTROMECHANICAL DEVICES –

Part 41: RF MEMS circulators and isolators

1 Scope

This part of IEC 62047 specifies the terminology, essential ratings and characteristics, and measuring methods of RF (Radio Frequency) MEMS (Micro-Electro-Mechanical Systems) circulators and isolators.

2 Normative references

The following documents are referred to in the text in such a way that some or all of their content constitutes requirements of this document. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

IEC 60747-1:2010, *Semiconductor devices – Part 1: General*

IEC 60749-10, *Semiconductor devices – Mechanical and climatic test methods – Part 10: Mechanical shock*

IEC 60749-12, *Semiconductor devices – Mechanical and climatic test methods – Part 12: Vibration, variable frequency*

IEC 60749-21, *Semiconductor devices – Mechanical and climatic test methods – Part 21: Solderability*

IEC 60749-22, *Semiconductor devices – Mechanical and climatic test methods – Part 22: Bond strength*

IEC 62047-1, *Semiconductor devices – Micro-electromechanical devices – Part 1: Terms and definitions*

IEC TS 61967-3, *Integrated circuits – Measurement of electromagnetic emissions – Part 3: Measurement of radiated emissions – Surface scan method*

3 Terms and definitions

For the purposes of this document, the terms and definitions given in IEC 62047-1 and the following apply.

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